

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of )  
Shigeo IRIE )  
Japanese Priority Application No. 2000-192459 ) Attn: Applications  
Japanese Priority Date: June 27, 2000 ) Branch  
For: PATTERN FORMING METHOD AND )  
APPARATUS FOR FABRICATING )  
SEMICONDUCTOR DEVICE ) Date: June 26, 2001

JC929 U.S. PTO  
09/891192  
06/26/01

#2  
D.G.  
9-21-01

INFORMATION DISCLOSURE STATEMENT


Honorable Commissioner for Patents  
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99,  
it is requested that the reference listed on the attached Form PTO-1449 be made of  
record in the above-identified application.

A copy of this reference is submitted herewith in accordance with 37 C.F.R.  
1.98(a).

Respectfully submitted,

  
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